

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application

Inventor(s): Pavel N. Laptev

Appln. No.: 10/633,839

Confirm. No.: 5260

Filed: August 4, 2003

Title: SYSTEM FOR, AND METHOD OF, ETCHING A
SURFACE ON A WAFER

PATENT APPLICATION

Art Unit: 1753

Examiner: McDonald, Rodney Glenn

Customer No. 23910

AMENDMENT AND REPLY

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria VA 22313-1450

Sir:

This Reply is in response to the Final Office Action mailed January 31, 2007.

Please amend the above-identified application as follows:

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 7 of this paper.